

FIG. 1

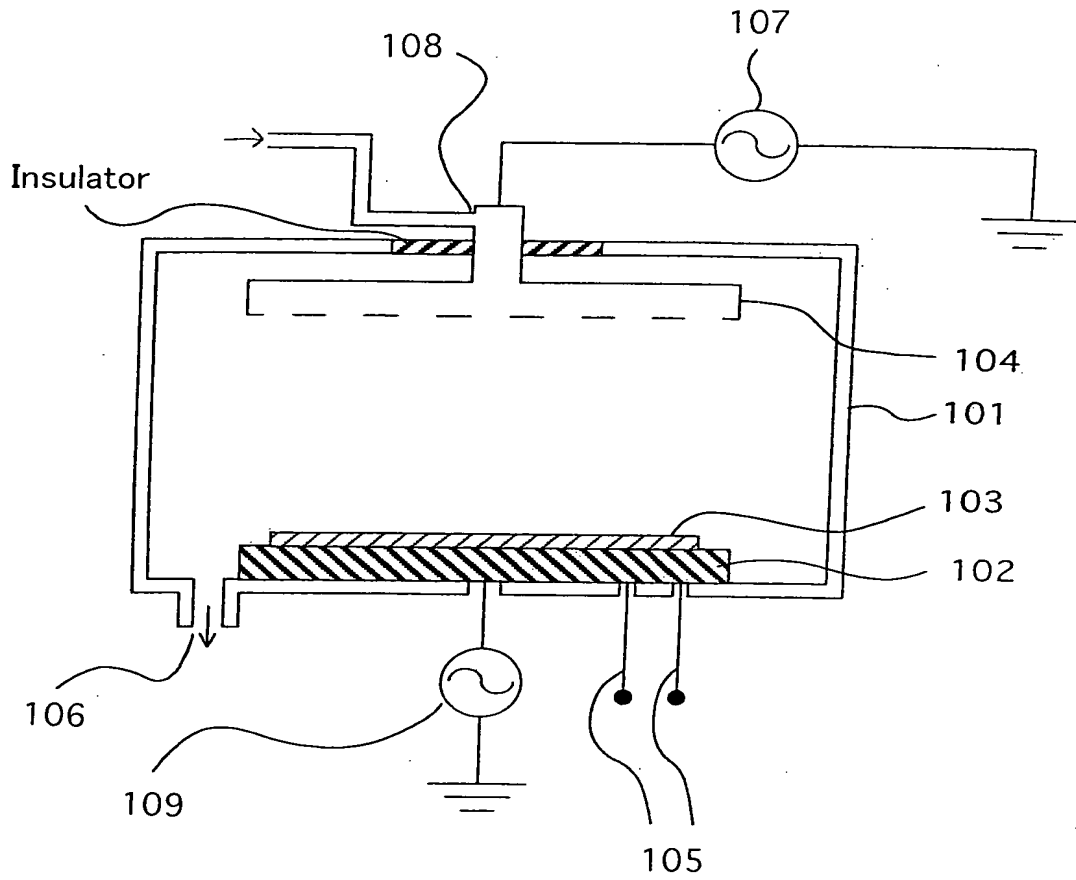
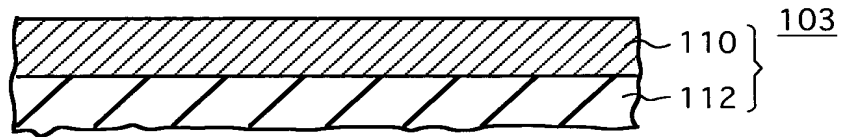


FIG. 2A



Processing with Plasma



FIG. 2B

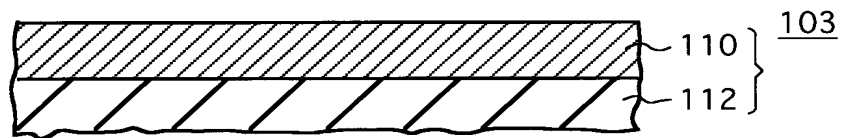


FIG. 2C

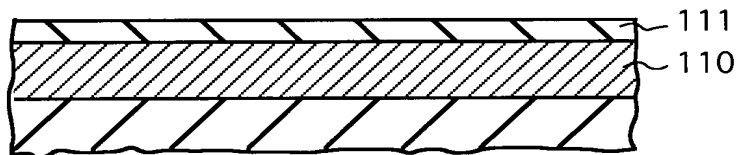


FIG. 3

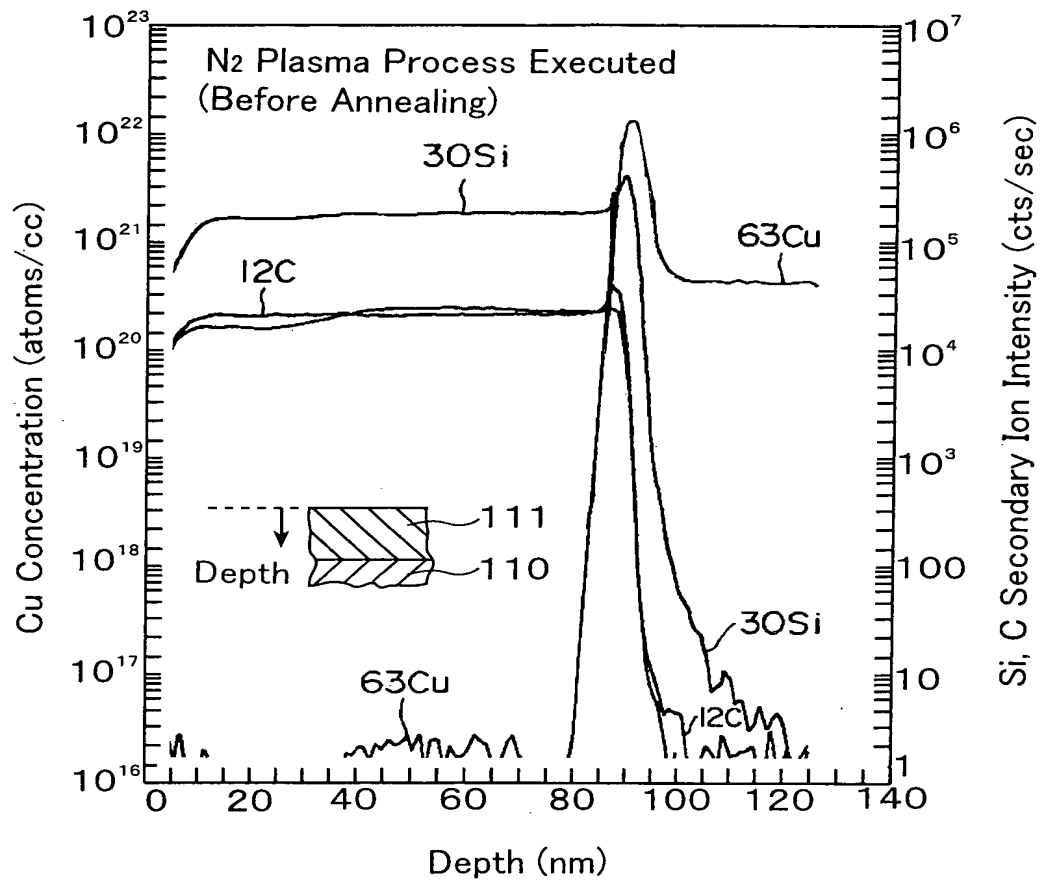


FIG. 4

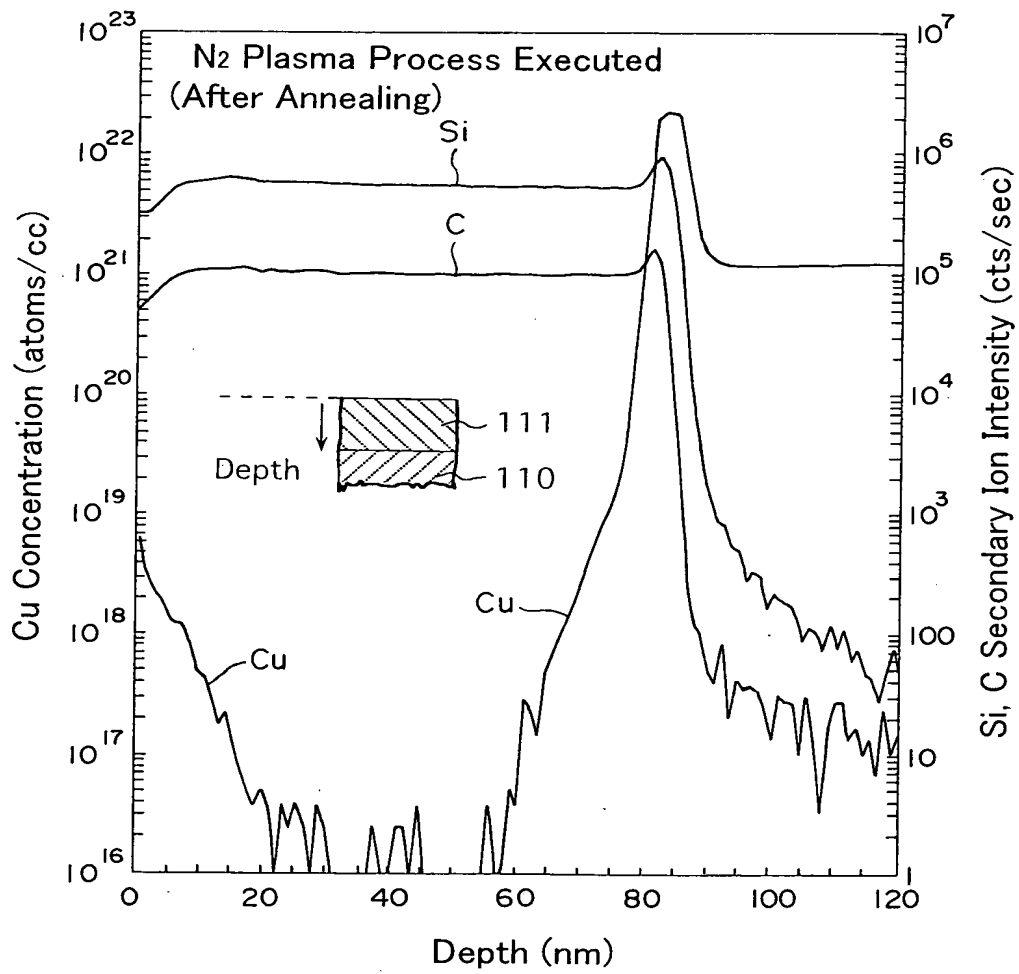


FIG. 5

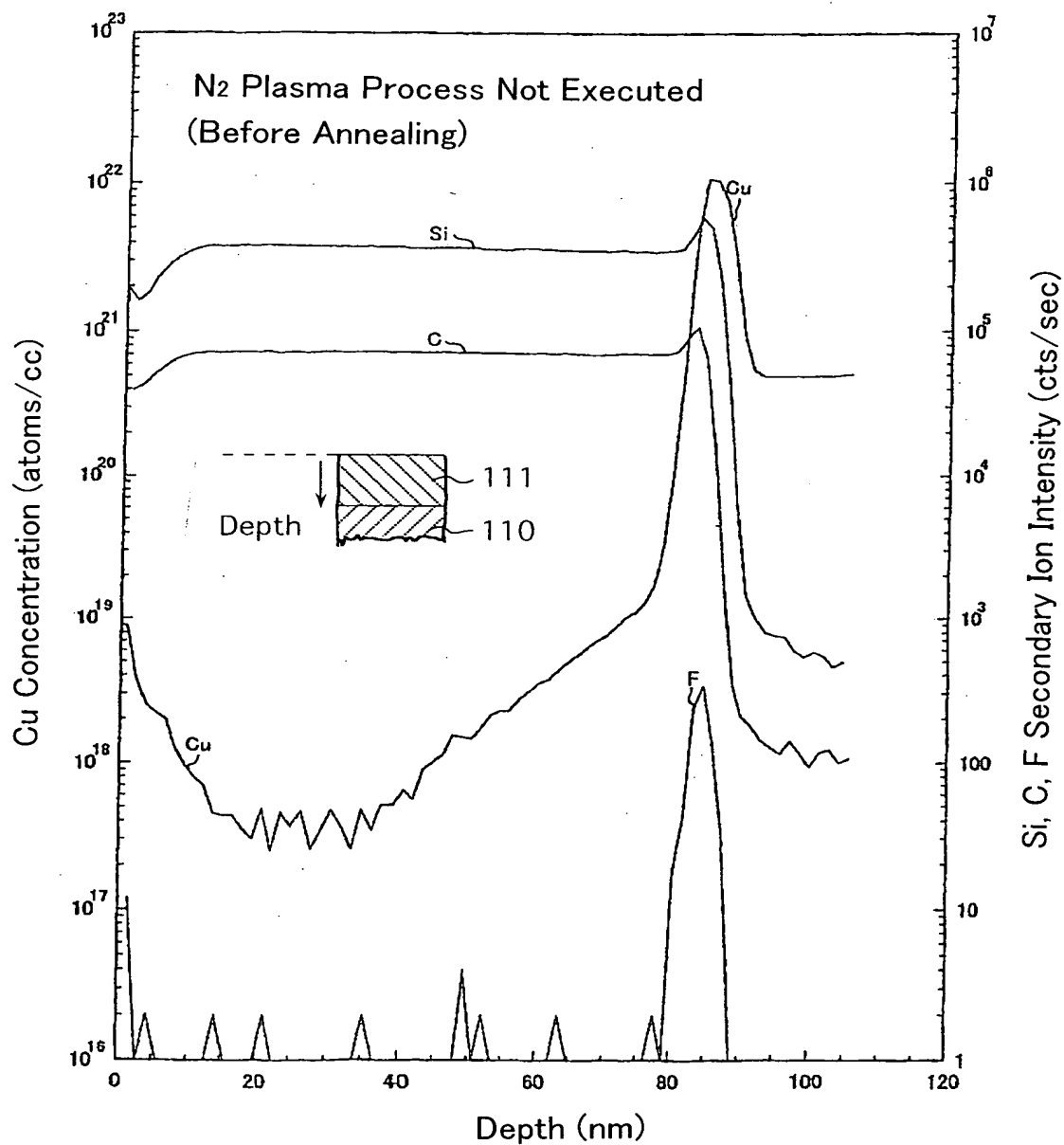


FIG. 6

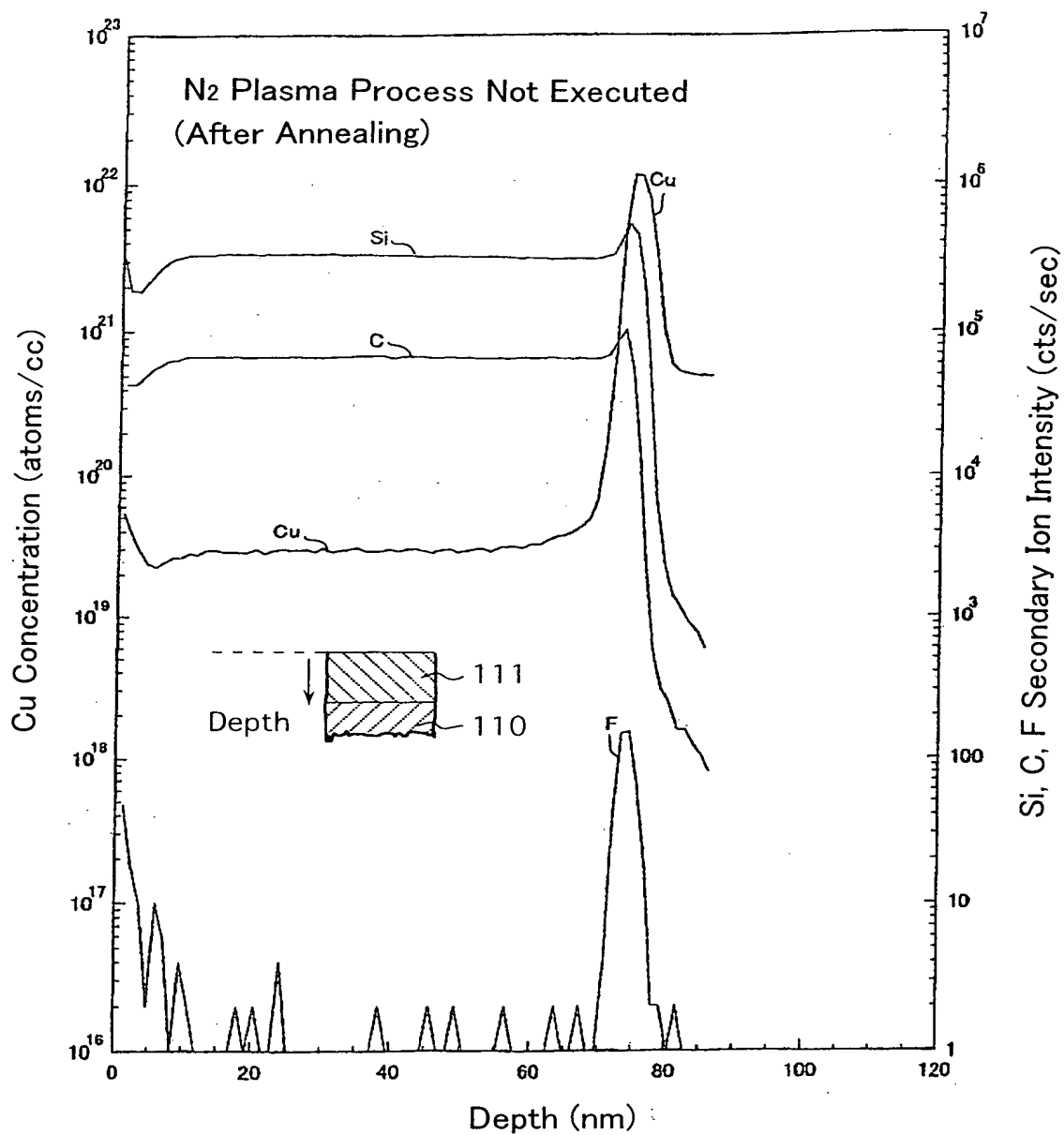


FIG. 7A

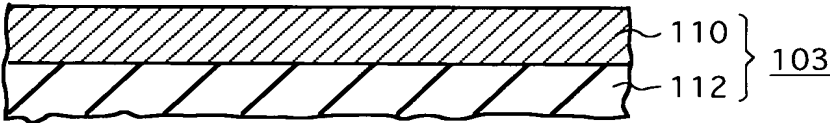


FIG. 7B

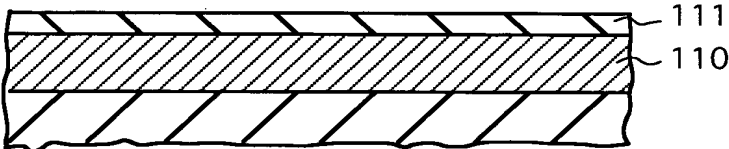


FIG. 7C

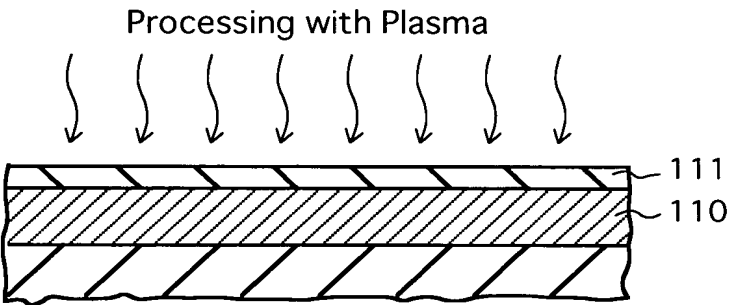


FIG. 8

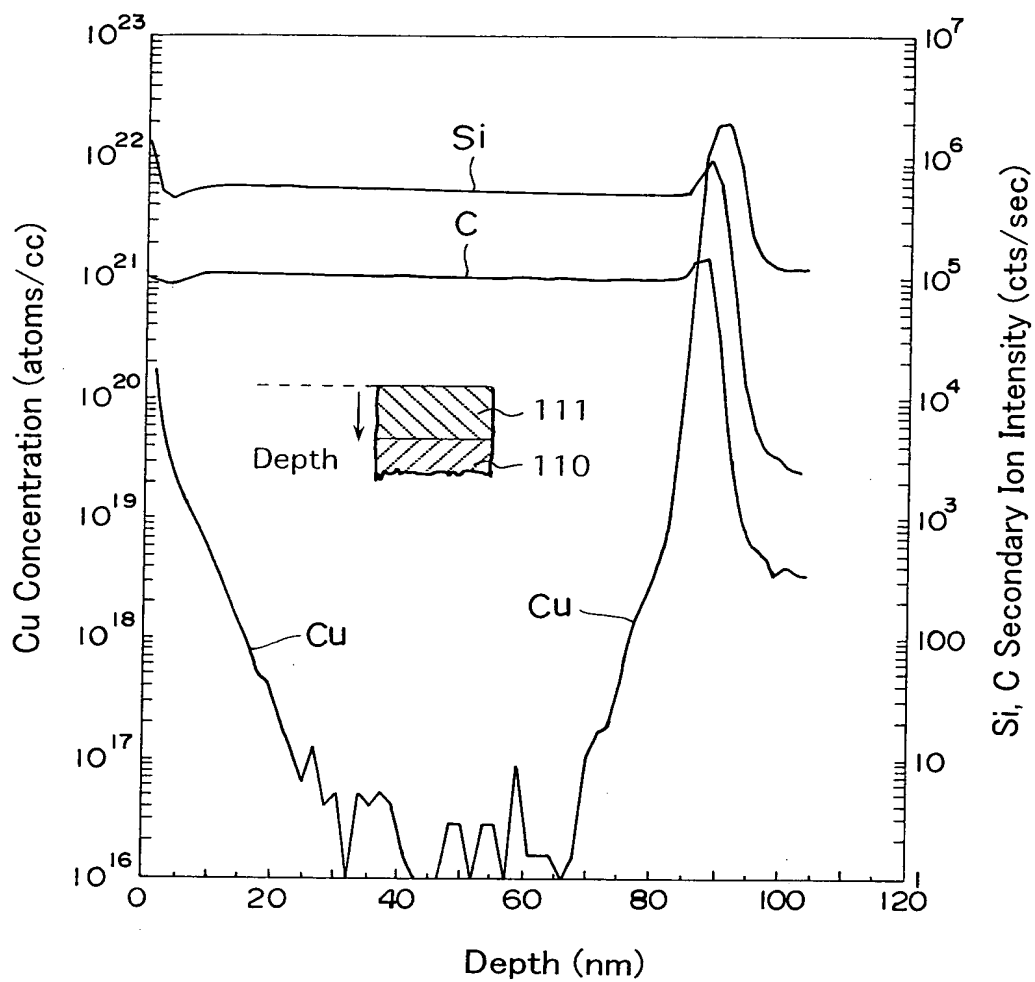
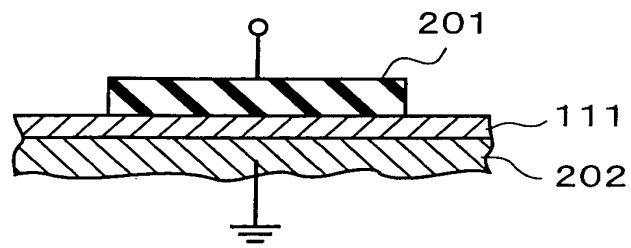


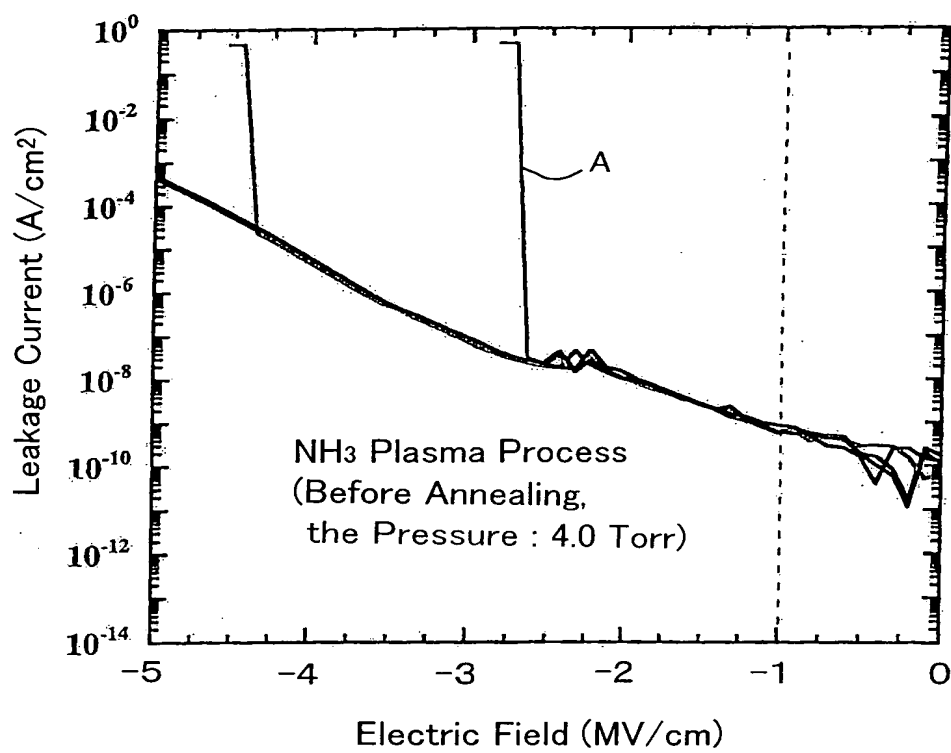


FIG. 9



00211 58988660

FIG. 10



000211-58988660

FIG. 11

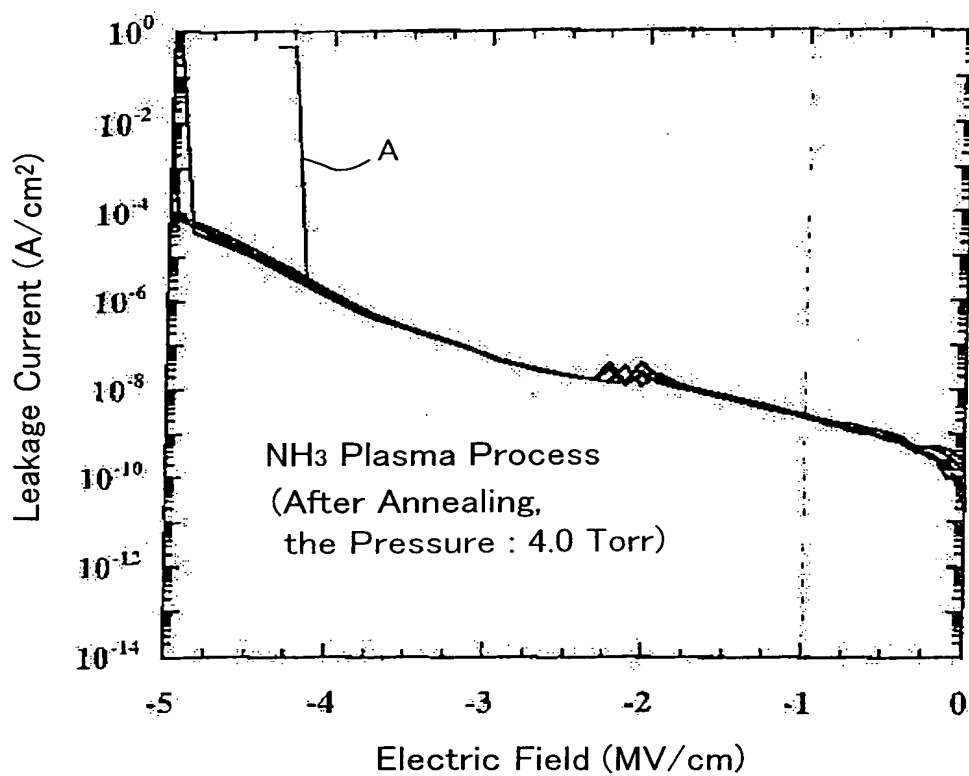


FIG. 12A

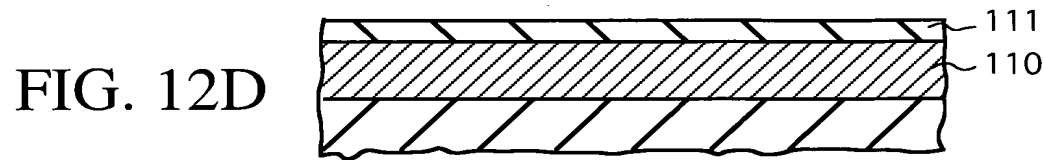
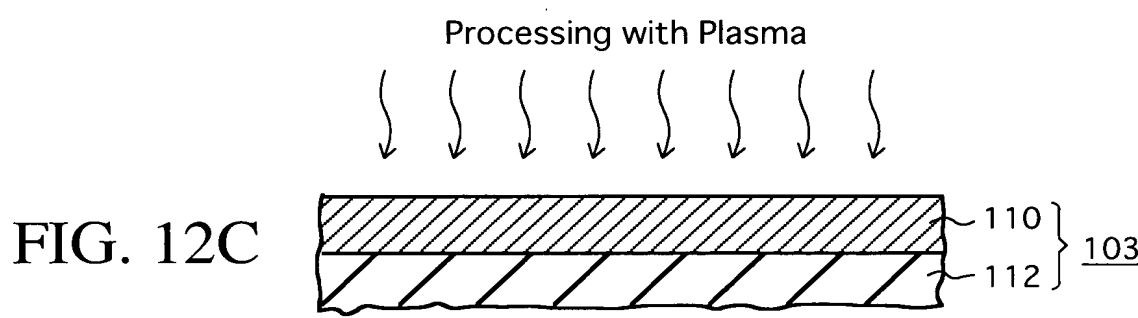
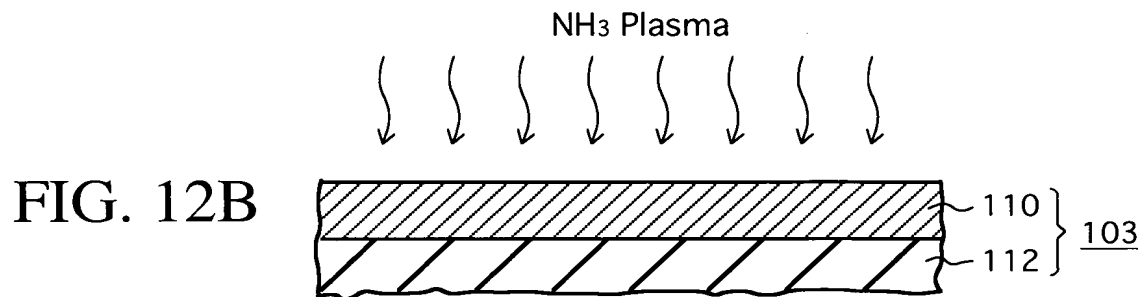


FIG. 12E

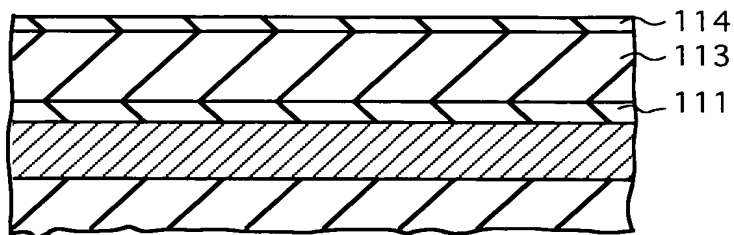


FIG. 12F

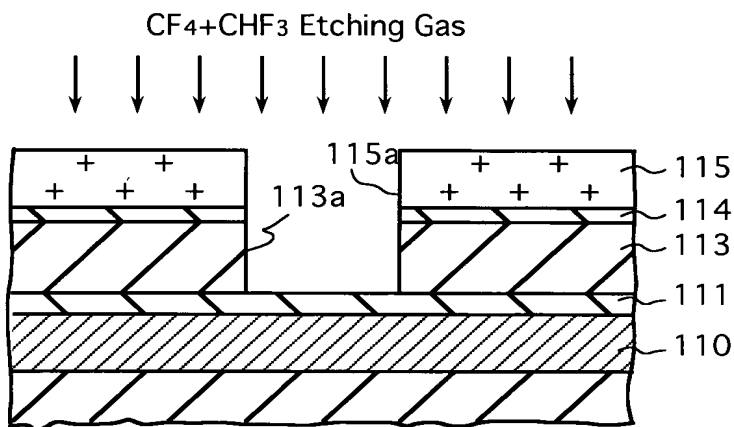
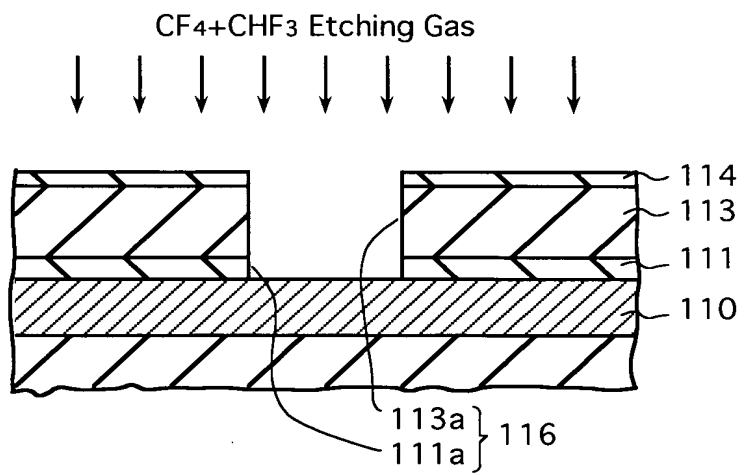


FIG. 12G



09988585.112001

FIG. 12H

